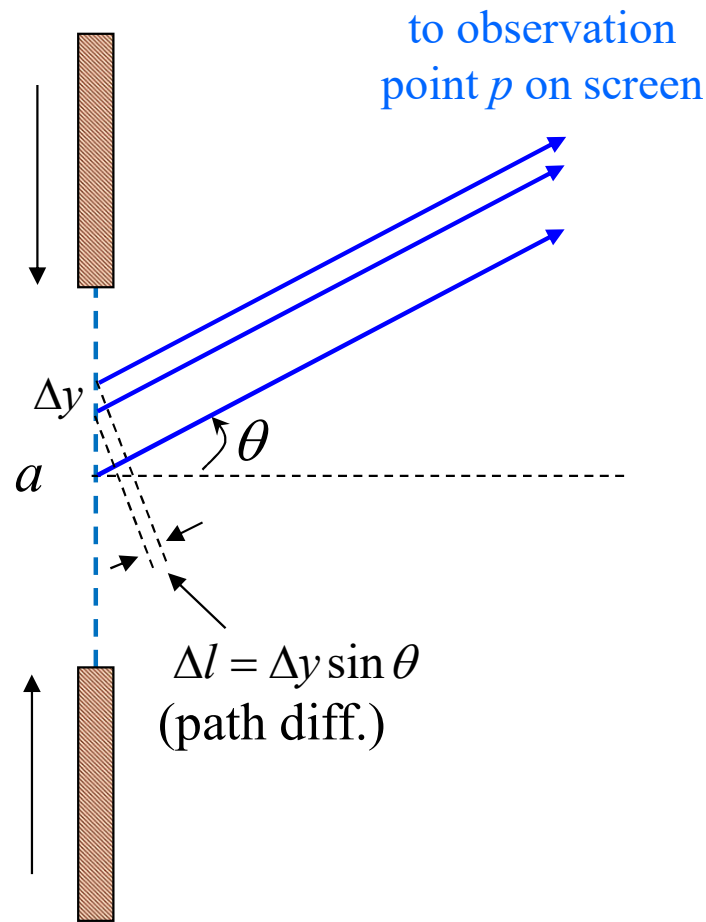


# Intensity in Single-Slit Pattern



Divide the wave front at the slit into  $N$  (large #) smaller strips/wavelets.

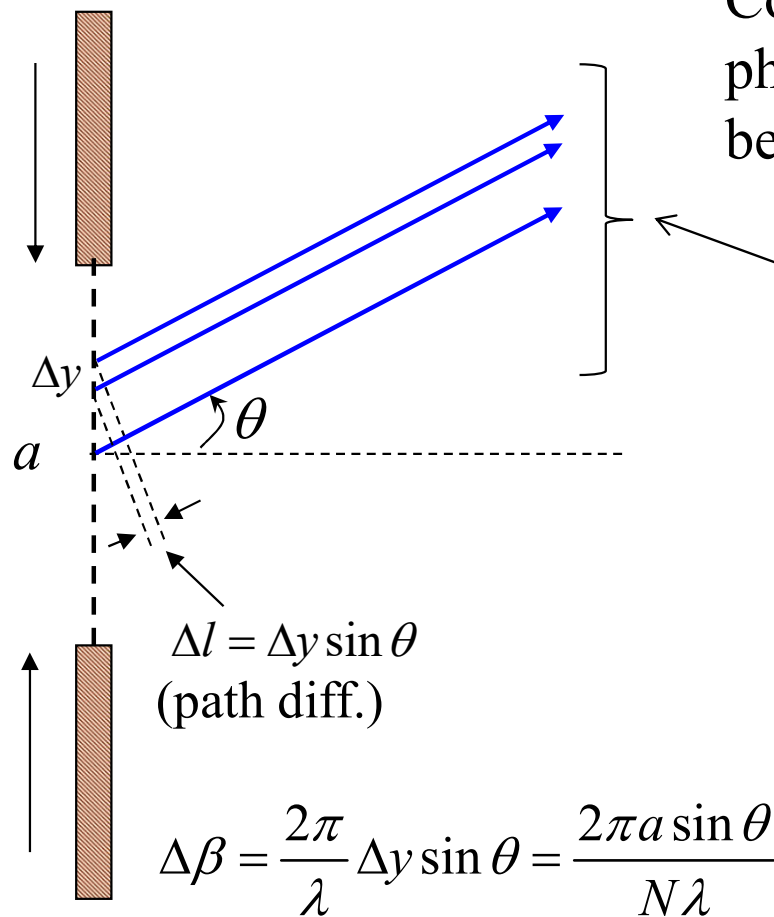
$\Delta y = a / N \rightarrow$  size of each small strip

$\Delta l = \Delta y \sin \theta \rightarrow$  small path diff. bet adj. strips

If  $E_0$  is the magnitude of the incoming wave, then the  $E$ -field from each wavelet will have a magnitude of

$$\Delta E = E_0 / N$$

# Intensity in Single-Slit Pattern (Phasors)



Consider the electric field from each wavelet as a phasor  $\Delta\vec{E}$ , the resultant electric field  $E_p$  at  $p$  can be calculated as the phasor sum of all the  $\Delta\vec{E}$ 's.

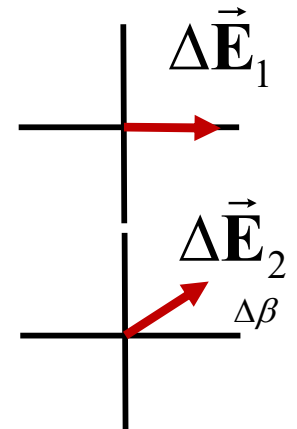
$$\Delta\vec{E}_1, \Delta\vec{E}_2, \dots, \Delta\vec{E}_N$$

$$\Delta E_1 = \frac{E_0}{N} \cos(\omega t)$$

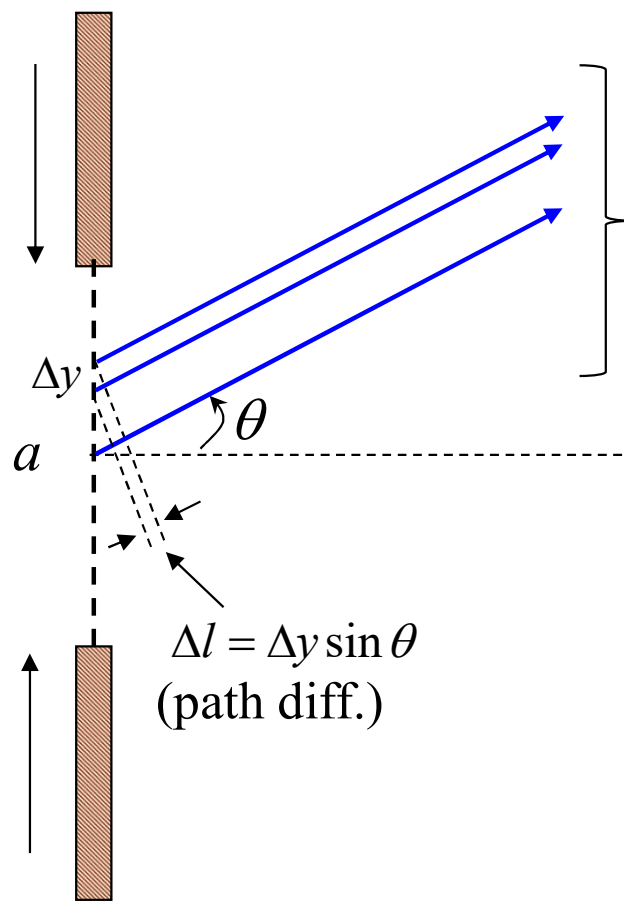
$$\Delta E_2 = \frac{E_0}{N} \cos(\omega t + \Delta\beta)$$

$\vdots$

$$\Delta E_N = \frac{E_0}{N} \cos(\omega t + (N-1)\Delta\beta)$$



# Intensity in Single-Slit Pattern (Phasors)



$$\Delta \vec{E}_1, \Delta \vec{E}_2, \dots, \Delta \vec{E}_N$$

For each pair of adjacent phasors, there is a path difference  $\Delta l$

and this path difference induces a phase difference  $\Delta \beta$  between adjacent phasors.

$$\frac{\Delta \beta}{2\pi} = \frac{\Delta l}{\lambda} \quad \rightarrow \quad \Delta \beta = \frac{2\pi}{\lambda} \Delta l = \frac{2\pi}{\lambda} \Delta y \sin \theta$$

with  $\Delta y = \frac{a}{N}$ , we then have  $\Delta \beta = \frac{2\pi a \sin \theta}{N \lambda}$

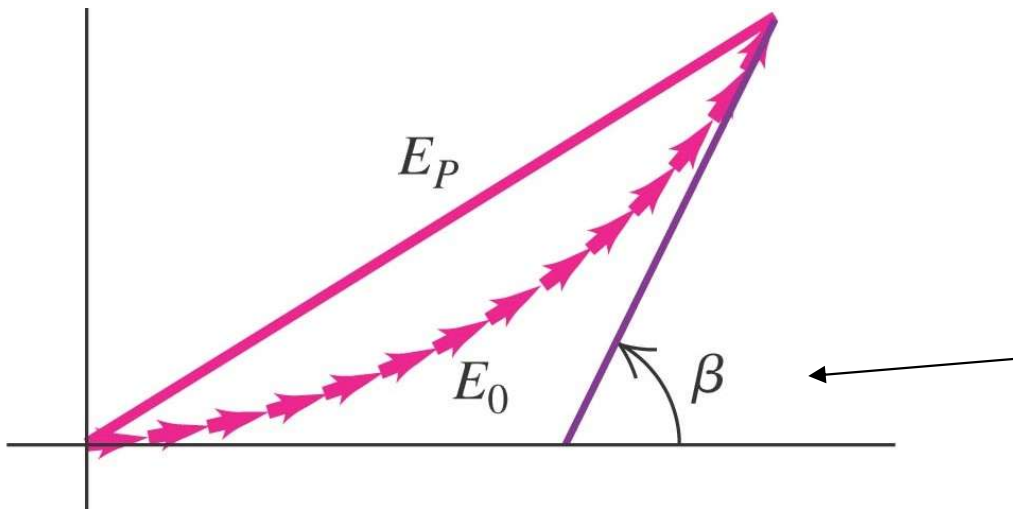
# Phase Difference from Path Difference

Considering the phasor sum of all  $N$  phasors, the *total* phase difference  $\beta$  is,

$$\beta = N\Delta\beta = N\left(\frac{2\pi}{\lambda}\Delta y \sin\theta\right)$$

$$\beta = \frac{2\pi}{\lambda}(N\Delta y)\sin\theta = \frac{2\pi}{\lambda}a\sin\theta$$

Note, the total phase difference  $\beta$  is again a function of the angular location  $\theta$ .



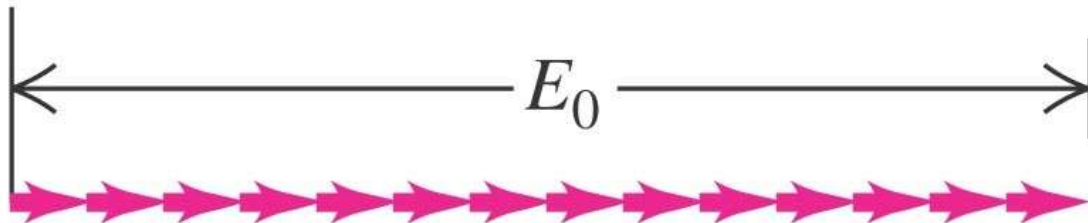
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NOTE: Similar to  $\phi$  earlier,  $\beta$  has to be in radian!

# Summing Phasors to Calculate $E_p$

---

Central Maximum ( $\Delta\beta = 0$ ,  $\beta = 0$ , straight ahead):

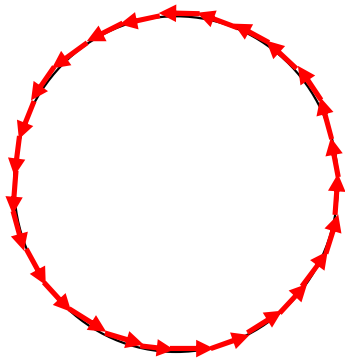


All phasors are *in phase*.

$$E_p = N\Delta E = E_0$$

# Summing Phasors to Calculate $E_p$

First Order Minimum ( $\beta = N \Delta\beta = 2\pi$ ):



1<sup>st</sup> minimum condition when last phasor's tip matches up *exactly* with the first phasor's end.

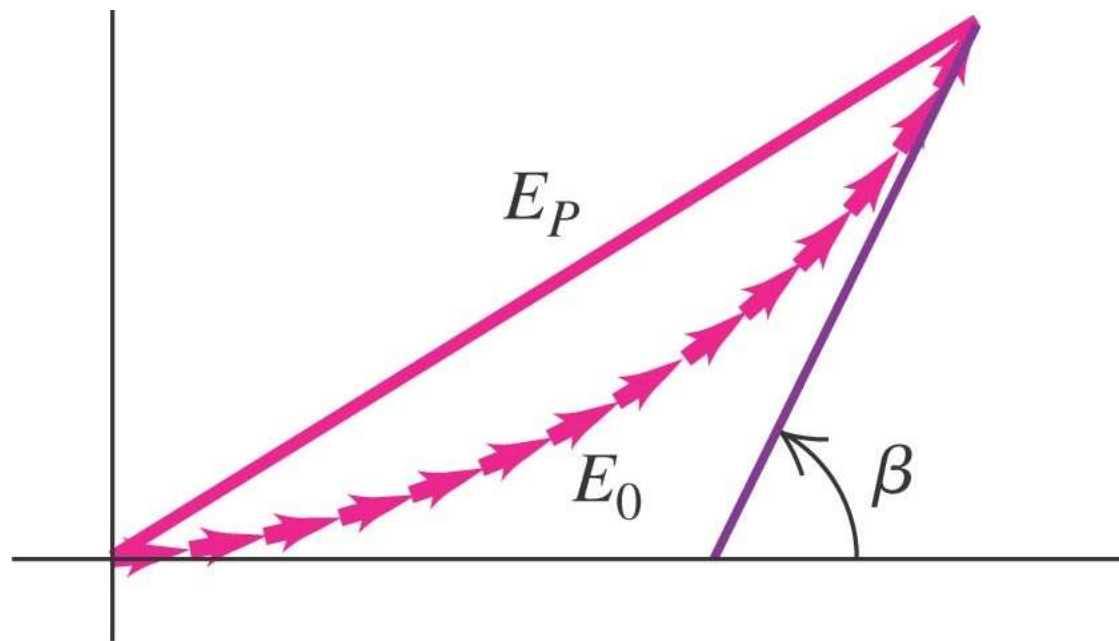
$$E_p = 0$$

Note:  $\beta = \frac{2\pi}{\lambda} a \sin \theta = 2\pi \rightarrow a \sin \theta = \lambda$

↑  
same condition as previously derived.

# Summing Phasors to Calculate $E_p$

Slightly away from Central Maximum ( $\Delta\beta > 0, \beta > 0$ ):



$\beta$  is the phase diff. between the first and the last phasors.

$$E_p < E_0$$

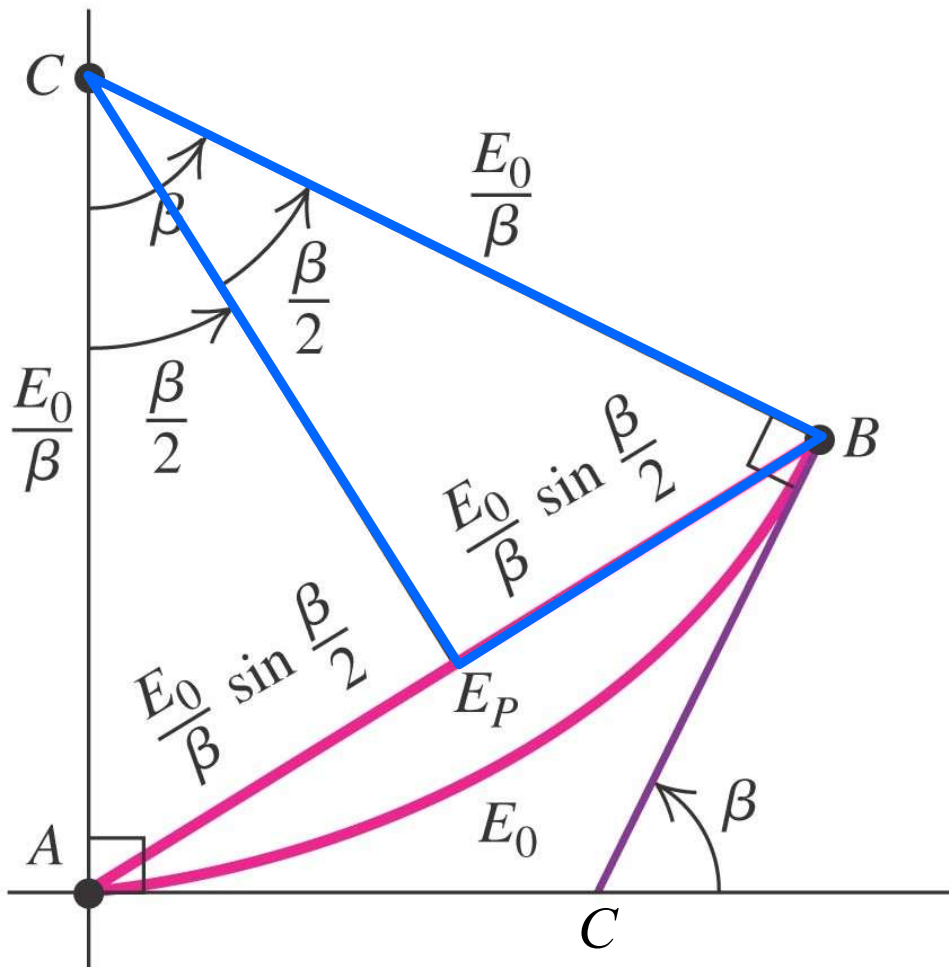
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$$\beta = \frac{2\pi}{\lambda} a \sin \theta$$





# Intensity in Single-Slit Pattern



Lastly, from the **blue** right triangle,

$$\sin \frac{\beta}{2} = \frac{\overline{AB}/2}{E_0/B} \rightarrow \overline{AB} = E_p = E_0 \frac{\sin(\beta/2)}{\beta/2}$$

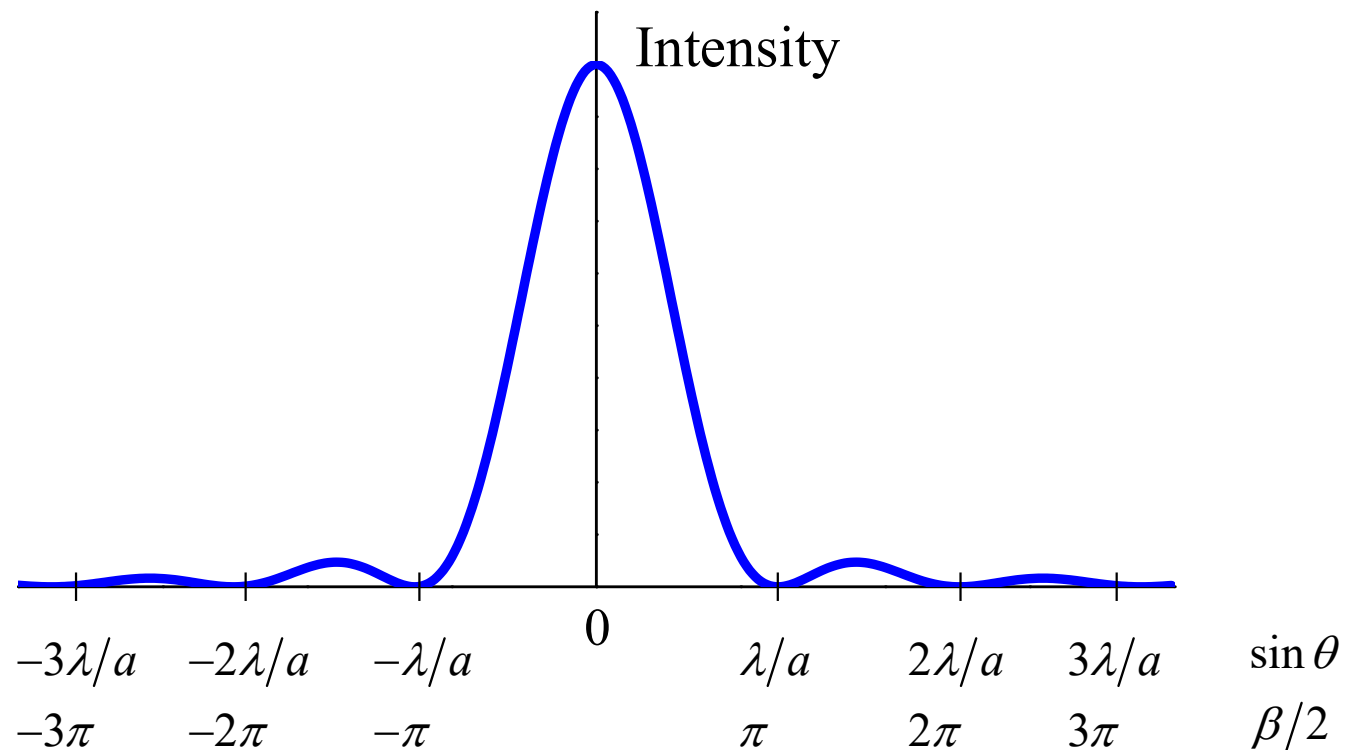
With  $I$  proportional to  $E_p^2$ ,

$$I = I_0 \left[ \frac{\sin(\beta/2)}{\beta/2} \right]^2$$

# Intensity in Single-Slit Pattern

Then, lastly with  $\beta = \frac{2\pi}{\lambda} a \sin \theta$ , the intensity of the pattern as a function of  $\theta$  is,

$$I = I_0 \left[ \frac{\sin(\pi a \sin \theta / \lambda)}{\pi a \sin \theta / \lambda} \right]^2$$



# Locating Mins & Maxs

Minimum:

requires that  $I = I_0 \left[ \frac{\sin(\beta/2)}{\beta/2} \right]^2 = 0$ , where  $\frac{\beta}{2} = \frac{\pi}{\lambda} a \sin \theta$

→  $\frac{\beta}{2} = \frac{\pi}{\lambda} a \sin \theta = m\pi$ ,  $m = \cancel{0}, \pm 1, \pm 2, \dots$

→  $a \sin \theta = m\lambda$  same condition as previously derived !

Note that  $\beta/2 = 0$  ( $m = 0$ ) is *not* a solution for a minimum !

In fact,  $\frac{\beta}{2} = \frac{\pi}{\lambda} a \sin \theta$  or  $\theta = 0$  is the central maximum with  $\lim_{\beta \rightarrow 0} \frac{\sin(\beta/2)}{\beta/2} = 1$

# Locating Mins & Maxs

---

## Maximum:

For single-slit Fraunhofer diffraction patterns, maximum occur *near*

$$\frac{\beta}{2} = \frac{3\pi}{2}, \frac{5\pi}{2}, \frac{7\pi}{2}, \dots \quad \text{but not exactly !}$$

To find the maximum exactly, we need to find the *extremum* for the intensity function, i.e.,

$$\frac{dI(x)}{dx} = \frac{d}{dx} \left( \frac{\sin x}{x} \right)^2 = 0 \quad \text{where } x = \frac{\beta}{2} = \frac{\pi}{\lambda} a \sin \theta$$

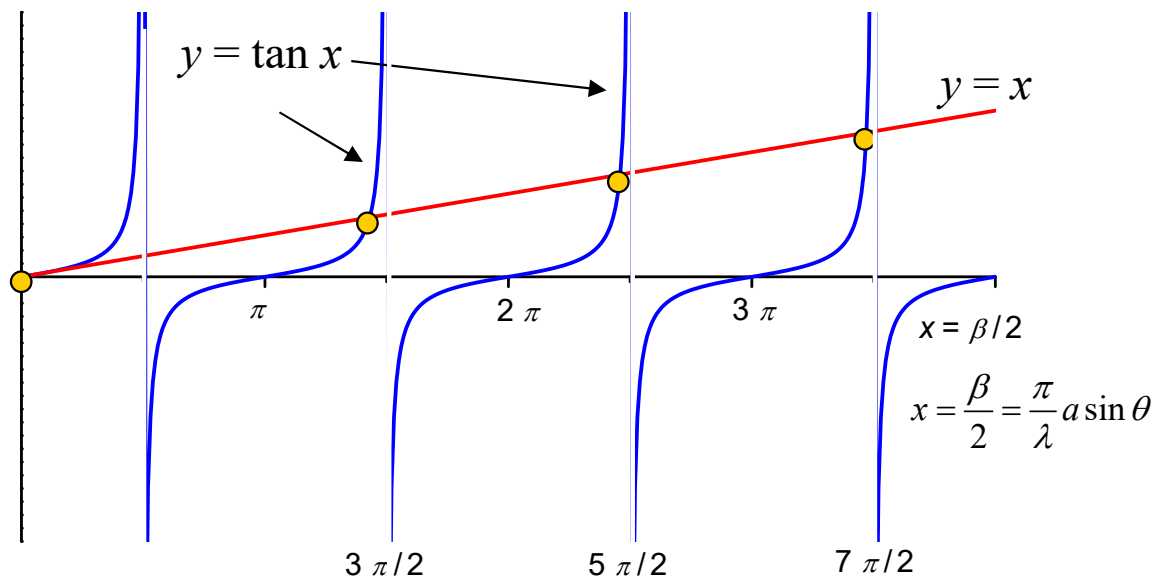
$$\longrightarrow \frac{d}{dx} \left( \frac{\sin x}{x} \right)^2 = 2 \left( \frac{\sin x}{x} \right) \left( \frac{\cos x}{x} - \frac{\sin x}{x^2} \right) = 0$$

# Locating Mins & Maxs

There are two solutions:

1.  $\frac{\sin x}{x} = 0 \quad \longrightarrow \quad x = m\pi \rightarrow \frac{\pi a \sin \theta}{\lambda} = m\pi \rightarrow a \sin \theta = m\lambda$   
(same *minimum* condition)

2.  $\frac{\cos x}{x} - \frac{\sin x}{x^2} = 0 \rightarrow x = \tan x$



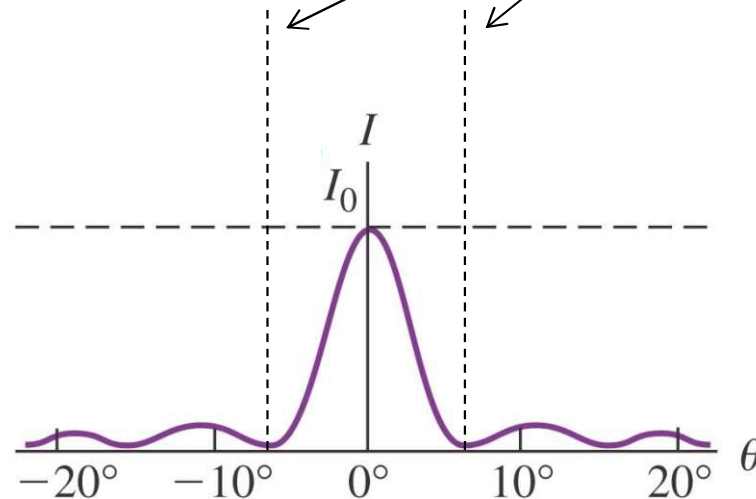
- intercepts are solutions to  $\tan x = x$ .

They give the locations of the *maximum* of the intensity function.

# Width of the Single-Slit Pattern

One can estimate the width of central max using the locations of 1<sup>st</sup> min on both left and right sides of the central max:

$$\sin \theta_1 = \pm \frac{\lambda}{a}$$

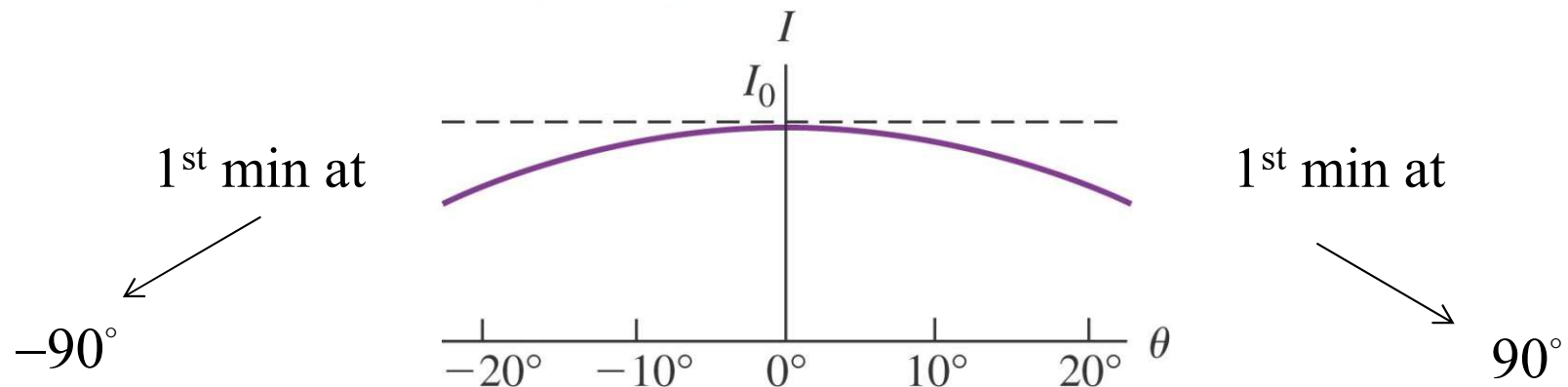


# Width of the Single-Slit Pattern

One can estimate the width of central max using the locations of 1<sup>st</sup> min on both left and right sides of the central max:

$$\sin \theta_1 = \pm \frac{\lambda}{a}$$

So, if  $a \leq \lambda$ , only one broad maximum is visible !



# Width of the Single-Slit Pattern

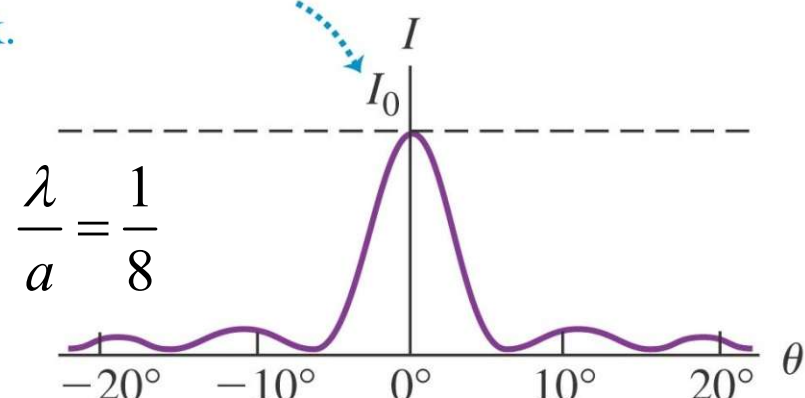
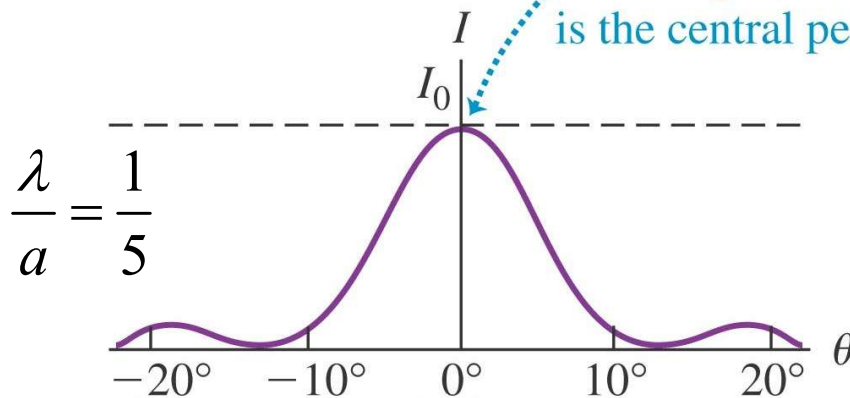
One can estimate the width of central max using the locations of 1<sup>st</sup> min on both left and right sides of the central max:

$$\sin \theta_1 = \pm \frac{\lambda}{a}$$

On the other hand, if  $\lambda < a$  and as  $\left| \frac{\lambda}{a} \right| \downarrow$

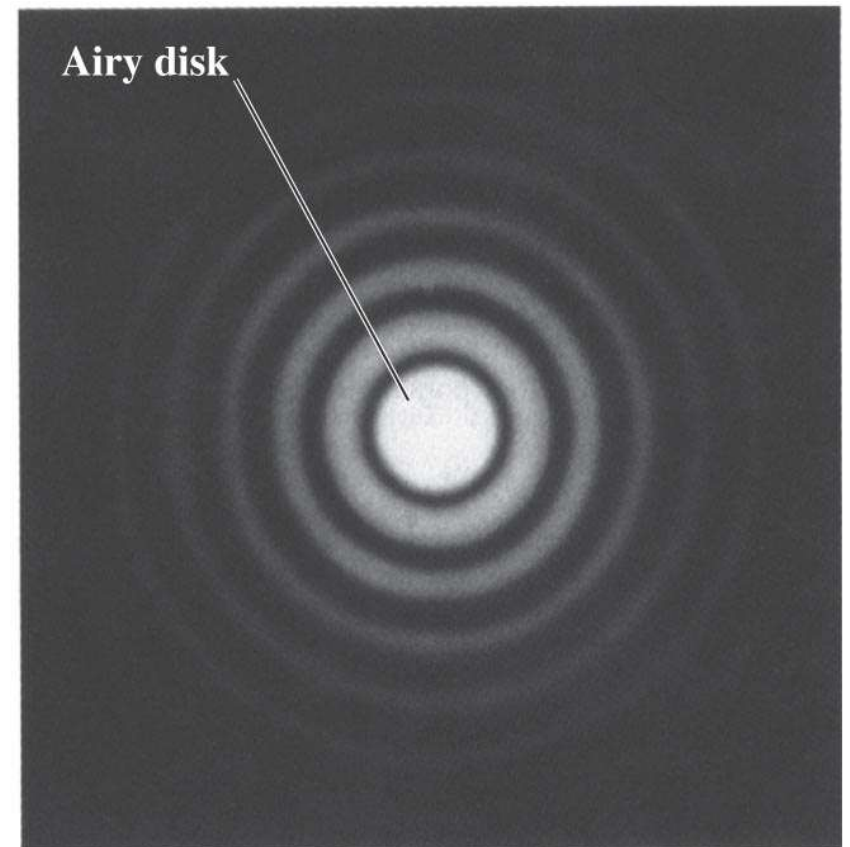
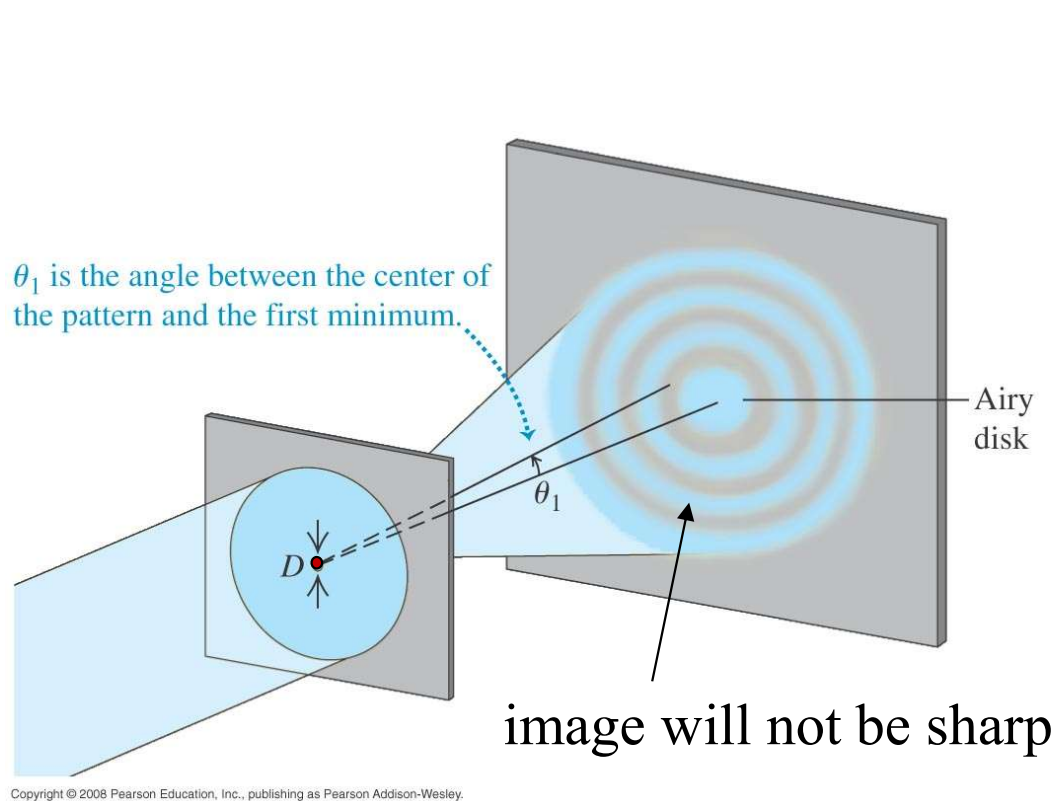
➔ 1<sup>st</sup> min moves closer (peak sharper)!

The wider the slit (or the shorter the wavelength), the narrower and sharper is the central peak.





# Resolving Power for Circular Apertures

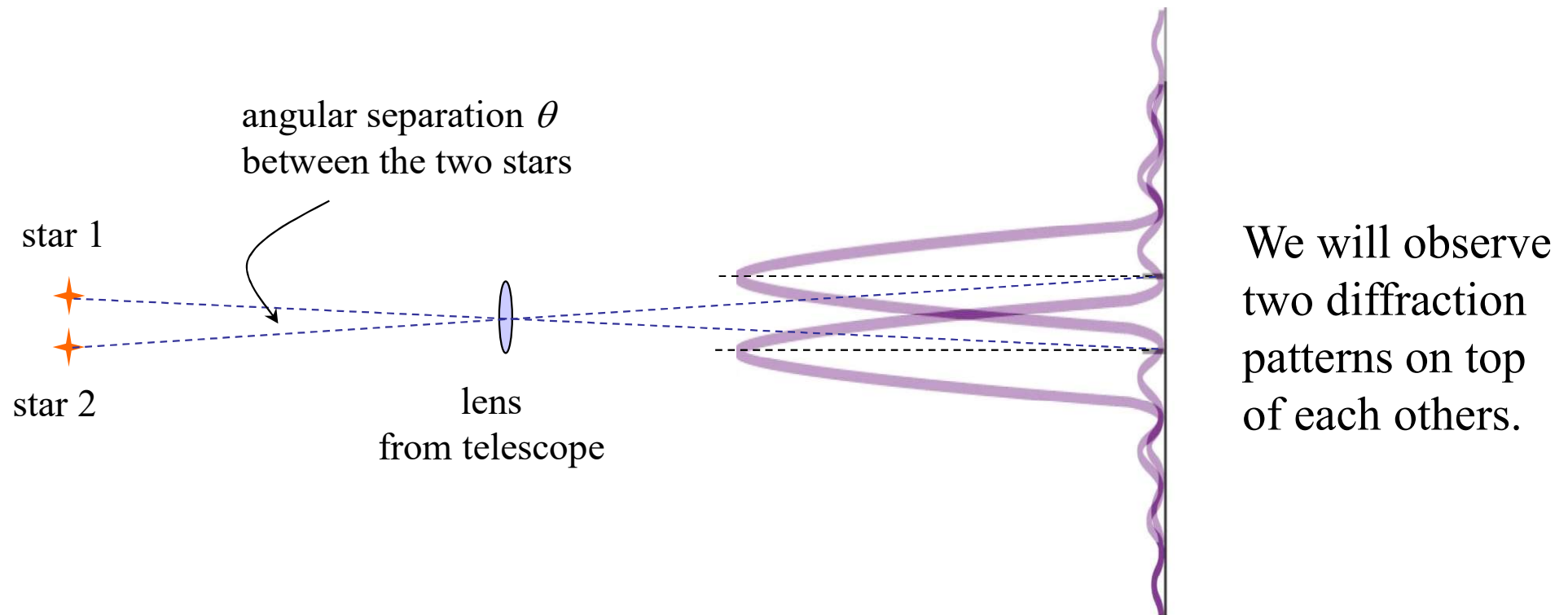


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Because of *diffraction*, light spreads out after passing thru circular apertures → this imposes *resolution limits* to commonly used optical instruments, such as microscopes and telescopes.

# Resolving Power for Circular Apertures

Consider two *non-coherent* point sources (so that they don't interfere), i.e. two distant stars,



# Resolving Power for Circular Apertures

---

The overlap of the two diffraction pattern might prevent one from discerning the two sources of light.

A workable criterion is called the **Rayleigh's Criterion** which is similar in spirit to our discussion for the resolving power for the diffraction grating:

The two diffraction pattern can be resolvable if the central max from one pattern is at least as far as the 1<sup>st</sup> min of the other image.

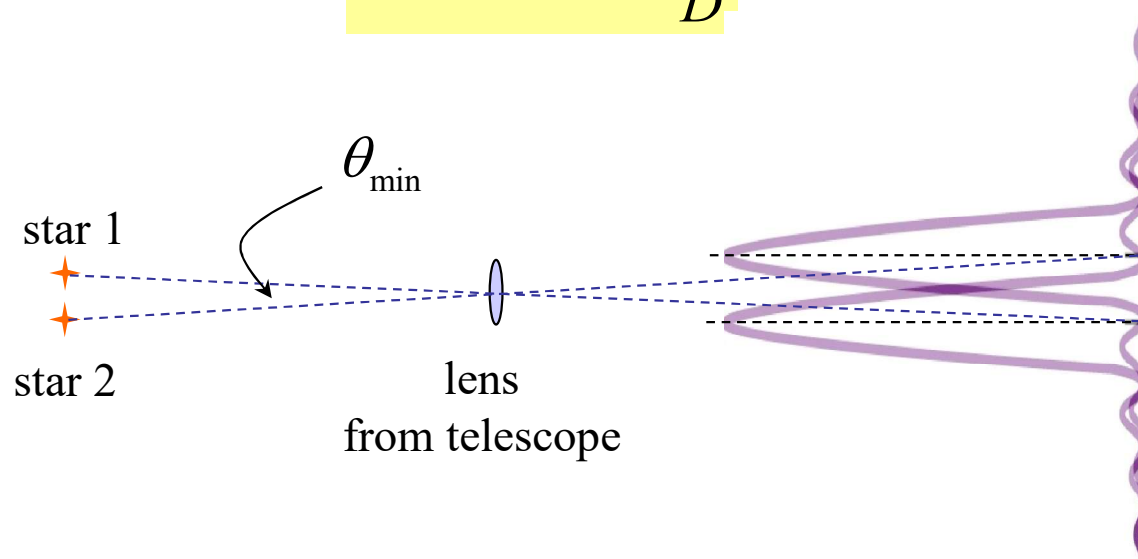
For circular aperture with diameter  $D$ , the angular location of the its 1<sup>st</sup> order diffraction minimum is:

$$\sin \theta_1 = 1.22 \frac{\lambda}{D} \quad (\text{"1.22" is a geometric factor})$$

# Resolving Power for Circular Apertures

The **Limit of Resolution** for a circular aperture is defined as the smallest angular separation between two light sources that can be resolved according to the *Rayleigh's Criterion* and it is given by:

$$\sin \theta_{\min} = 1.22 \frac{\lambda}{D}$$



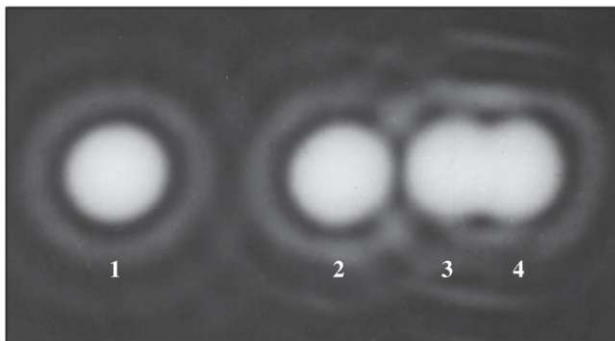
# Resolving Power for Circular Apertures

An optical device such as a telescope or microscope will have a *high Resolving Power* if it has a *small Limit of Resolution* ( $\theta_{\min}$  small) so that nearby objects with a small angular separation can be resolved.

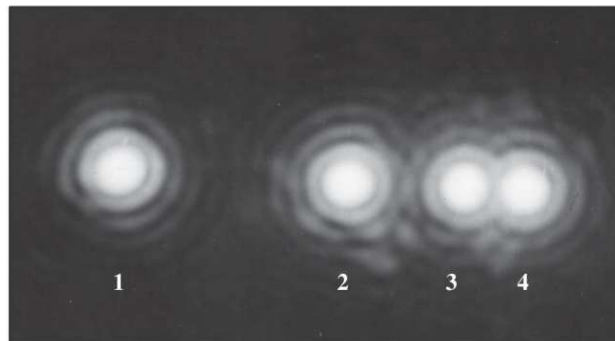
This gives the following ways to increase the Resolving Power:

- increase the diameter  $D \rightarrow$  use a bigger len/mirror in telescope
- decrease the wavelength  $\lambda \rightarrow$  use a shorter wavelength of light in chip production

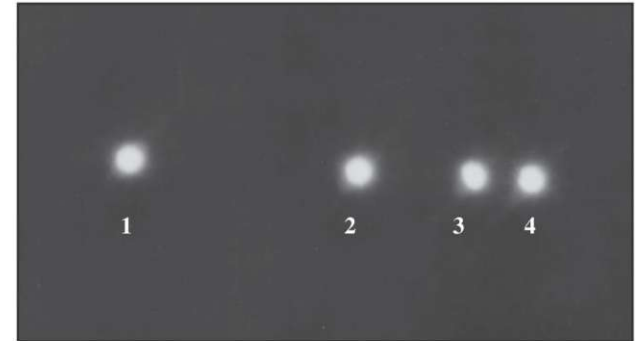
(a) Small aperture



(b) Medium aperture



(c) Large aperture



# Example 36.6: Resolving Power of a Camera Lens

---

**Given:**

f=50 mm

f-number of f/2

object distance 9.0m

wavelength = 500nm

What is the minimum distance between two points on the faraway object that one can resolve?

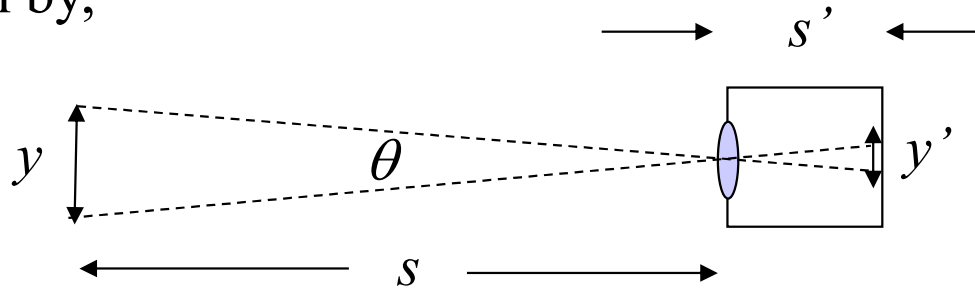
$$\text{f-number} = f/D \rightarrow D = f/\text{f-number} = 50\text{mm}/2 = 25 \text{ mm}$$

Rayleigh's Criterion gives:

$$\theta_{\min} \cong \sin \theta_{\min} = 1.22 \frac{\lambda}{D} = 1.22 \frac{500 \times 10^{-9} \text{ m}}{25 \times 10^{-3} \text{ m}} = 2.4 \times 10^{-5} \text{ rad}$$

# Example 36.6: Resolving Power of a Camera Lens

For a simple lens, we know that the angular separation of two points on the object is given by,



$$\theta \cong \left| \frac{y}{s} \right| = \left| \frac{y'}{s'} \right|$$

$y \rightarrow$  separation of object points

$y' \rightarrow$  separation of the corresponding image points

$s \rightarrow$  object distance

$s' \rightarrow$  image distance

# Example 36.6: Resolving Power of a Camera Lens

---

Applying the minimum condition, we have,

$$2.4 \times 10^{-5} \text{ rad} = \frac{y}{s} \rightarrow y = 9.0\text{m}(2.4 \times 10^{-5} \text{ rad}) = 0.22\text{mm} \quad (\text{on object})$$

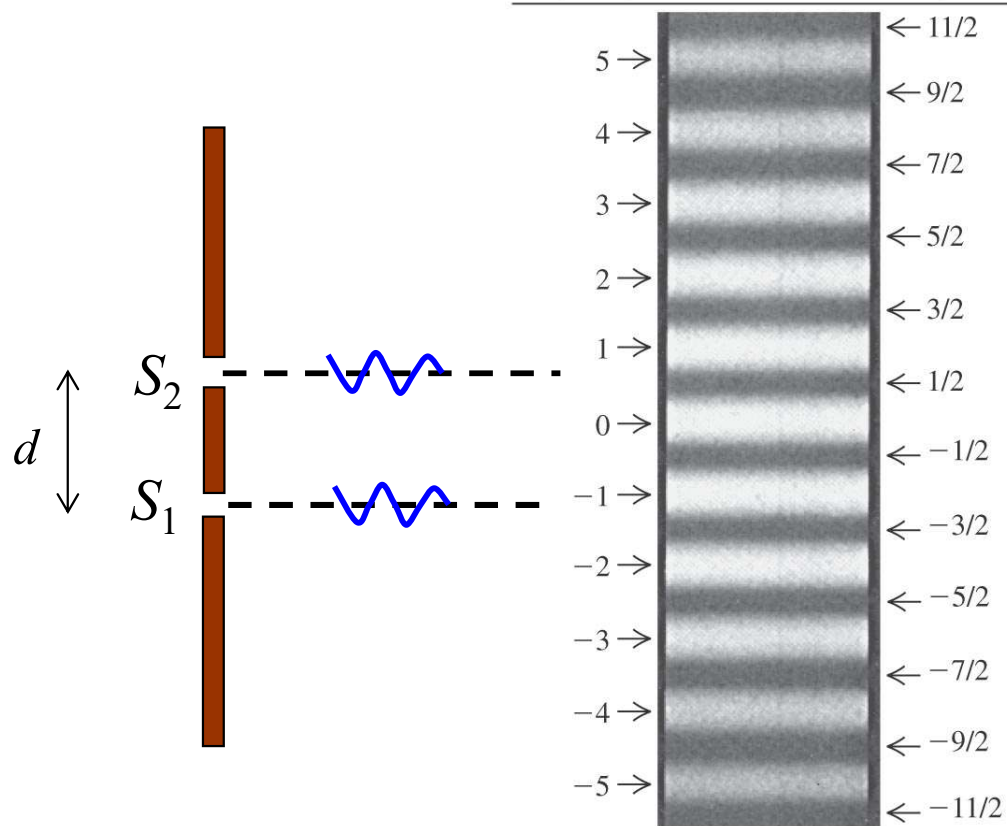
On the camera film, the image separation will be approximately,

$$2.4 \times 10^{-5} \text{ rad} = \frac{y'}{s'} \rightarrow y' = 50\text{mm}(2.4 \times 10^{-5} \text{ rad}) = 1.2 \times 10^{-3} \text{ mm} \quad (\text{on film})$$

$s' \sim f$  if image is focused on the film



# Double-Slit Interference Pattern (w/o diffraction)



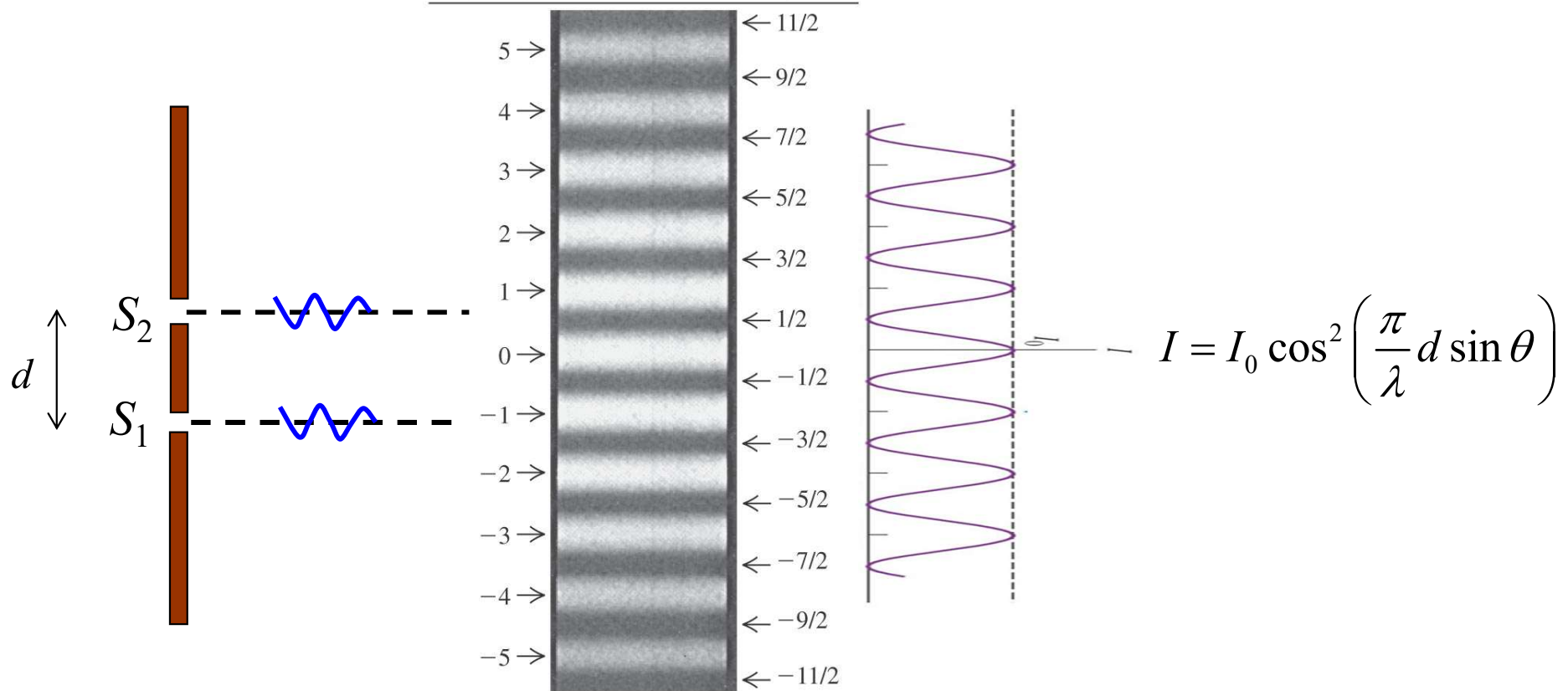
Constructive Interference:

$$d \sin \theta = m\lambda \quad (m = 0, \pm 1, \pm 2, \dots)$$

Destructive Interference:

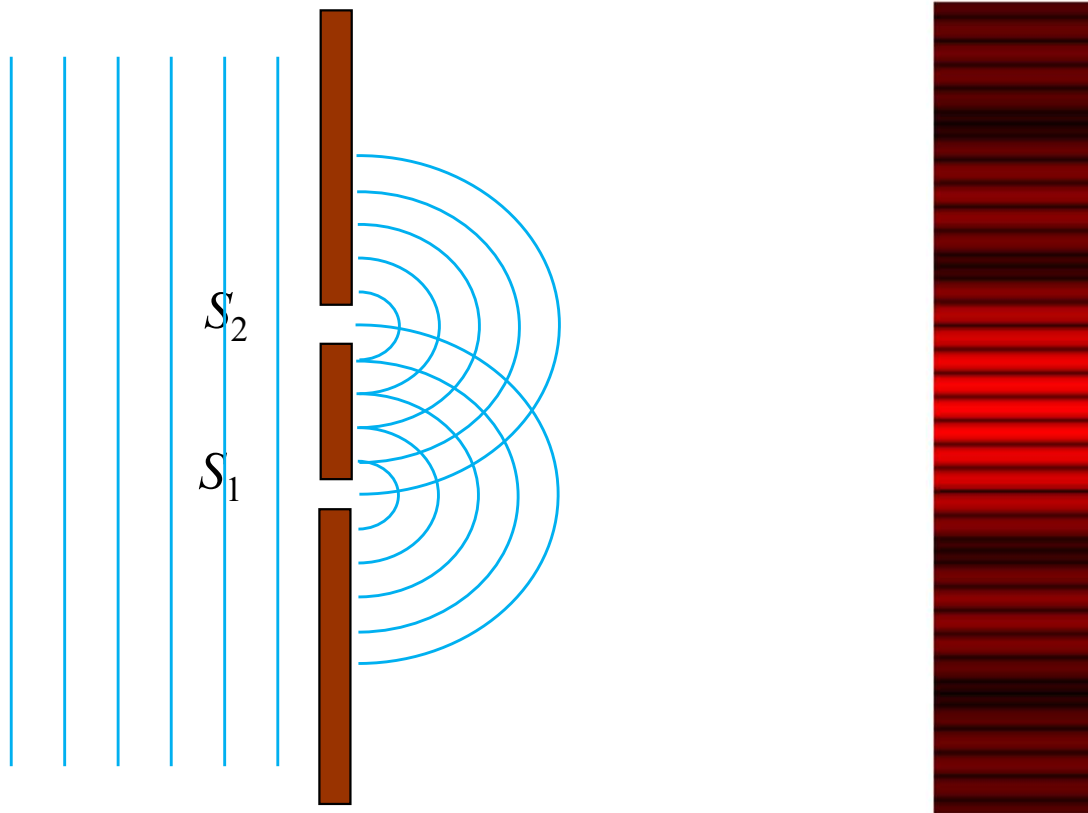
$$d \sin \theta = \left(m + \frac{1}{2}\right)\lambda \quad (m = 0, \pm 1, \pm 2, \dots)$$

# Double-Slit Interference Pattern (w/o diffraction)



# Intensity of Two-Slits Diffraction Patterns

With two slits, we have *diffraction* from the individual slits **and** *interference* from the two slits.



# Intensity of Two-Slits Diffraction Patterns

With two slits, we have *diffraction* from the individual slits **and** *interference* from the two slits.

The *combined* intensity is the *superposition* of the two effects:

$$I = I_0 \cos^2 \left( \frac{\phi}{2} \right) \left[ \frac{\sin(\beta/2)}{\beta/2} \right]^2$$

↑  
interference  
factor

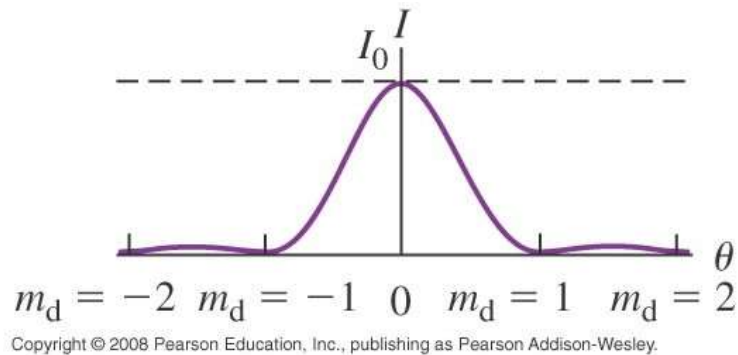
↑  
diffraction  
factor

where,  $\frac{\phi}{2} = \frac{\pi}{\lambda} d \sin \theta$  and  $\frac{\beta}{2} = \frac{\pi}{\lambda} a \sin \theta$

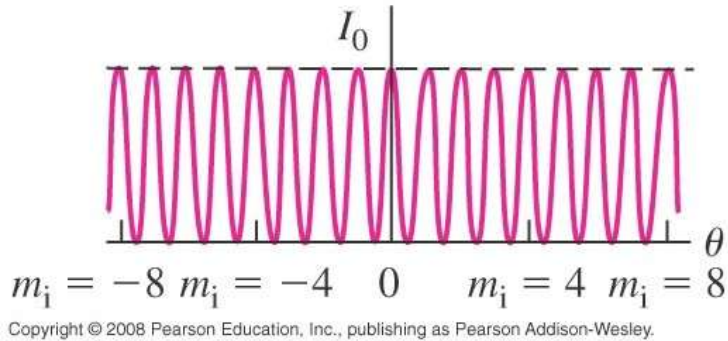
$d$  → separation bet. slits

$a$  → width of both slits

# Intensity of Two-Slits Diffraction Patterns

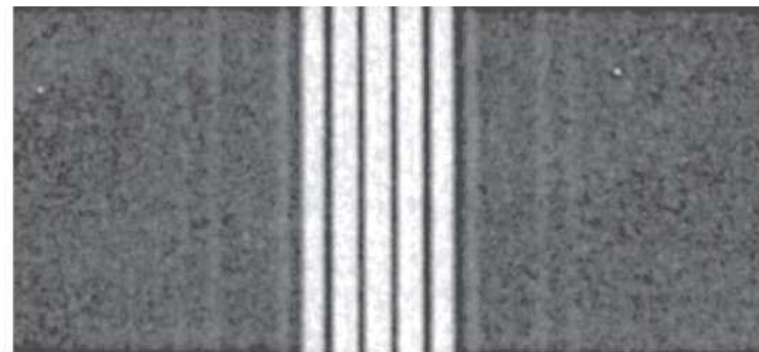
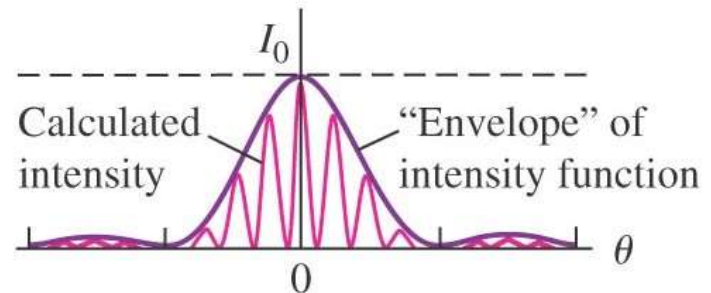


⊗



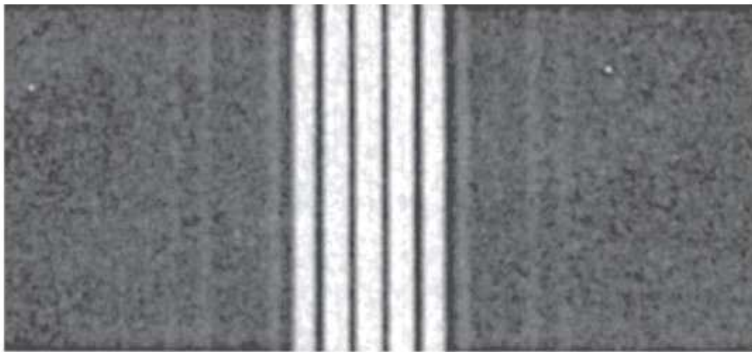
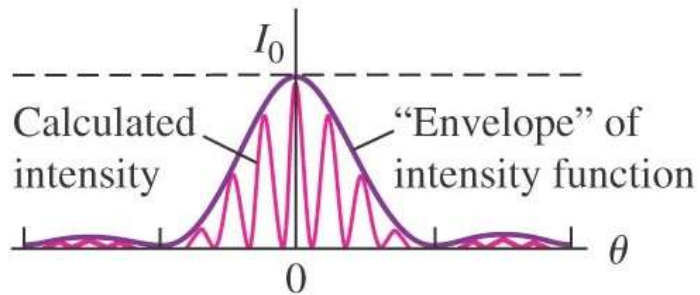
$$d = 4a$$

$$I = I_0 \cos^2 \left( \frac{\phi}{2} \right) \left[ \frac{\sin(\beta/2)}{\beta/2} \right]^2$$



For  $d = 4a$ , every fourth interference maximum at the sides ( $m_i = \pm 4, \pm 8, \dots$ ) is missing,

# Intensity of Two-Slits Diffraction Patterns



For  $d = 4a$ , every fourth interference maximum at the sides ( $m_i = \pm 4, \pm 8, \dots$ ) is missing,

$$d = 4a$$

$$I = I_0 \cos^2 \left( \frac{\phi}{2} \right) \left[ \frac{\sin(\beta/2)}{\beta/2} \right]^2$$

Interfer max:  $d \sin \theta = m\lambda$

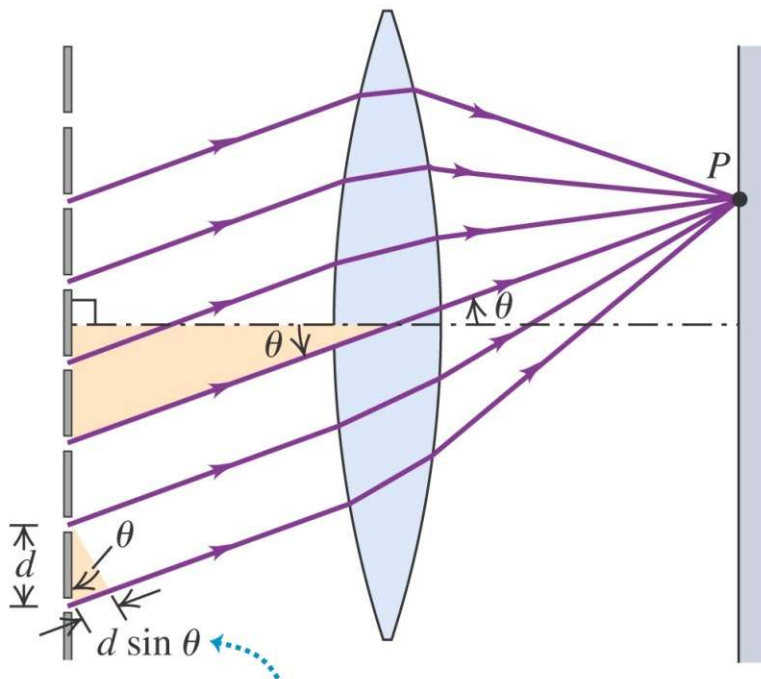
diff min:  $a \sin \theta' = m'\lambda$

When do they match?

$$\sin \theta = \sin \theta' \quad \longrightarrow \quad \frac{m}{m'} = \frac{d}{a} = 4$$

# Interference Patterns from Multiple Slits

Let consider an example with  
 $N=8$  slits,



Maxima occur where the path difference for adjacent slits is a whole number of wavelengths:  
 $d \sin \theta = m\lambda$ .

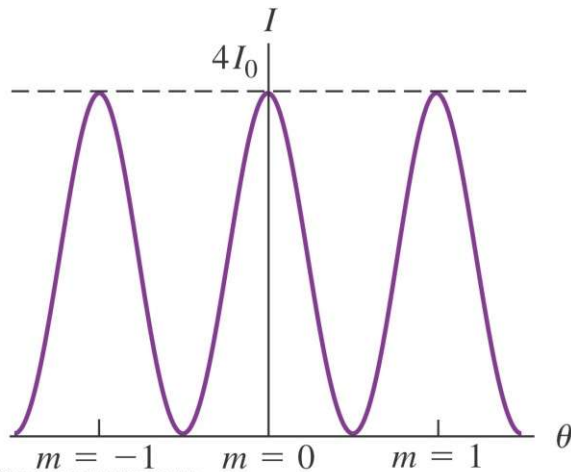
On the screen at  $P$ , **maximum** will occur at:

$$d \sin \theta = m\lambda, \quad m = 0, \pm 1, \pm 2, \dots$$

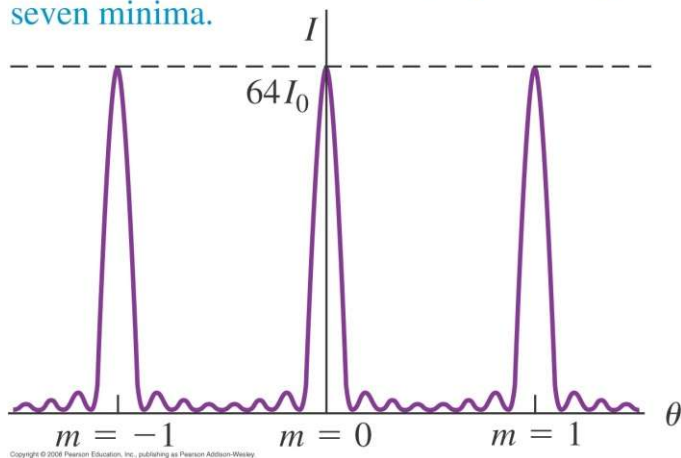
- when waves from adjacent slits have a path difference which is exactly  $m\lambda$ .
- This condition for maximums is the same for the two-slits patterns.

# Interference Patterns from Multiple Slits

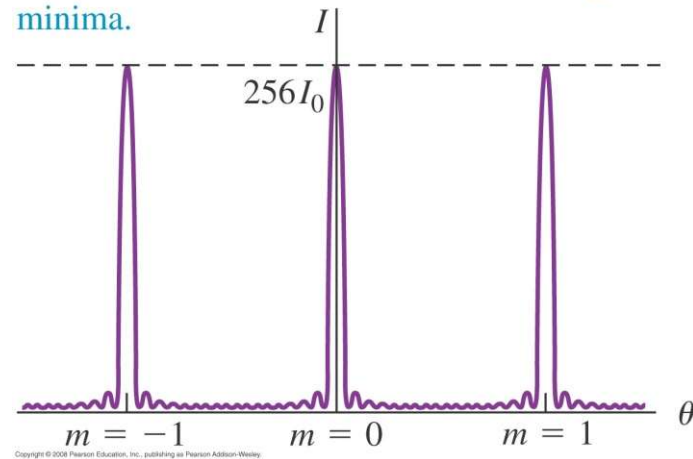
(a)  $N = 2$ : two slits produce one minimum between adjacent maxima.



(b)  $N = 8$ : eight slits produce taller, narrower maxima in the same locations, separated by seven minima.

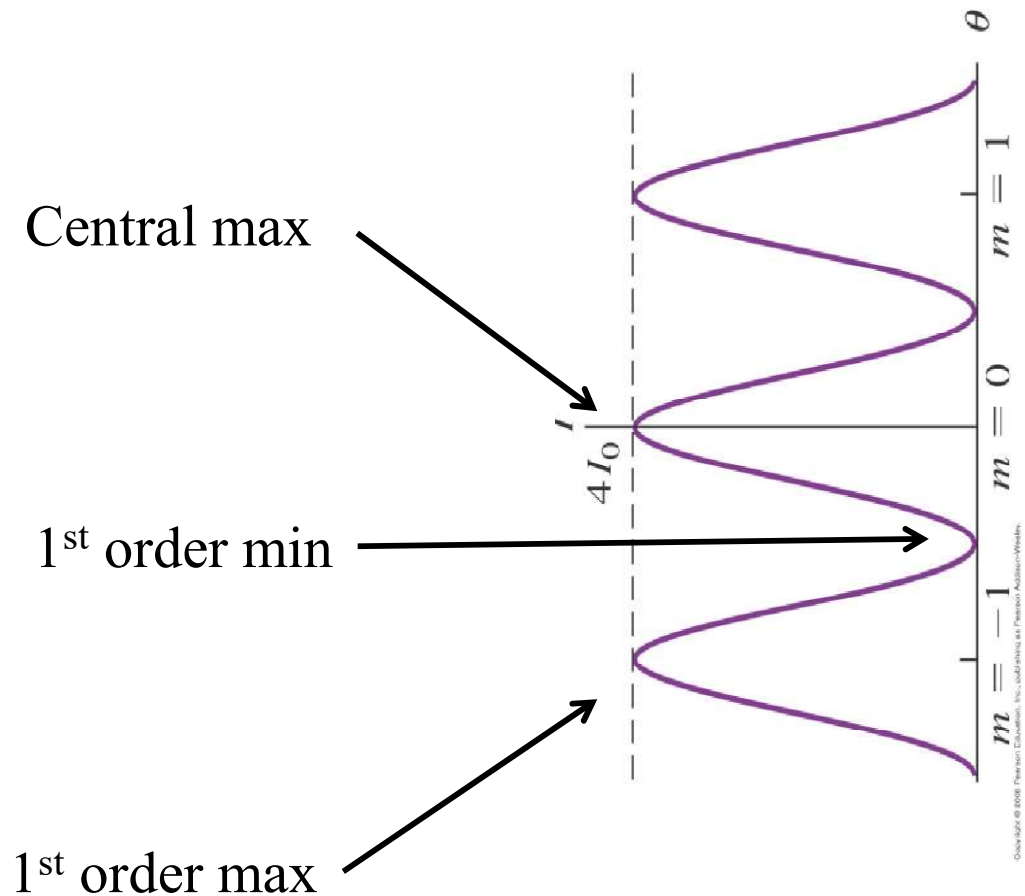
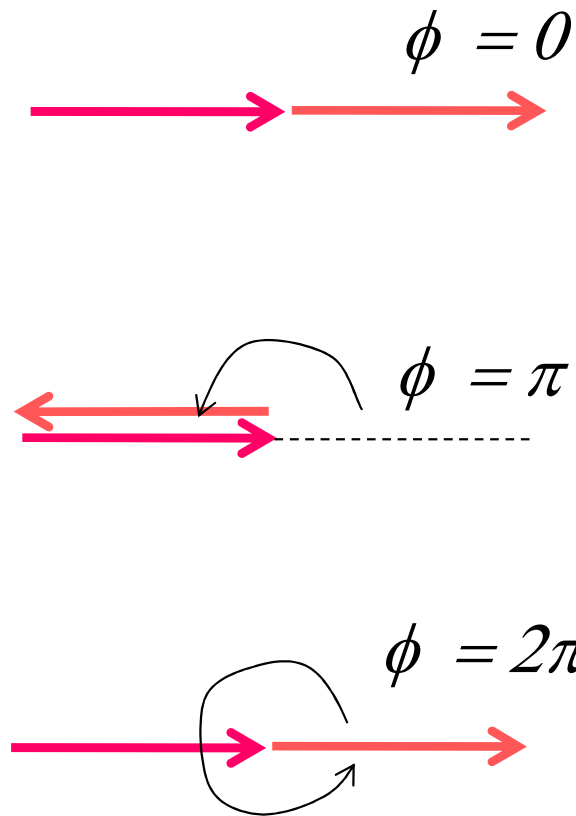


(c)  $N = 16$ : with 16 slits, the maxima are even taller and narrower, with more intervening minima.





# Interference Patterns from Two Slits



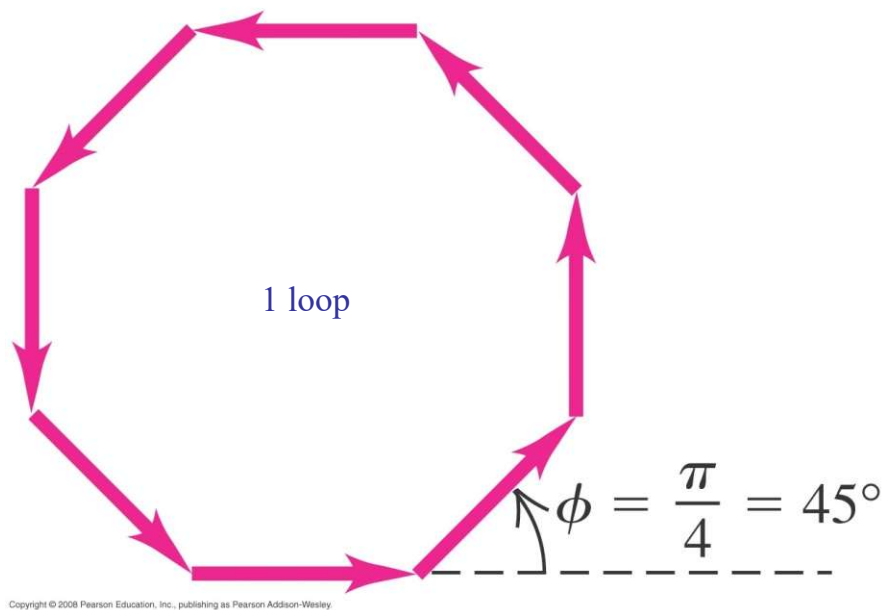
For  $N = 2$ , there is a single minimum exactly  $\frac{1}{2}$  way between 0 and  $2\pi$ .

$$\text{at } \phi = \pi = \frac{2\pi}{2} = \frac{2\pi}{N}$$

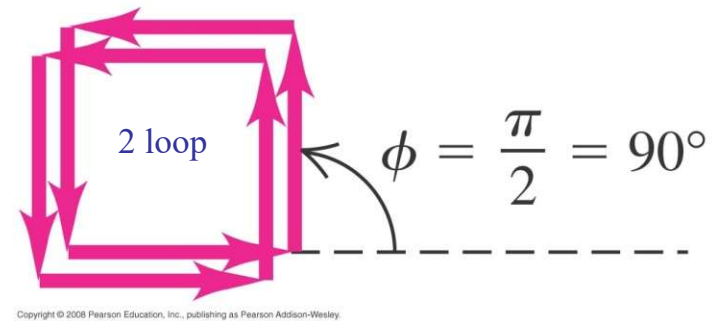
# Interference Patterns from Several Slits

Now, let look at the condition for the **minima** when  $\phi$  goes from 0 to  $2\pi$  for  $N=8$ :

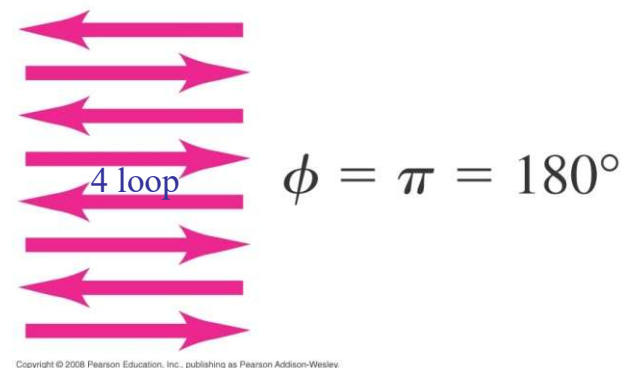
Phasor diagram for  $\phi = \frac{\pi}{4}$



Phasor diagram for  $\phi = \frac{\pi}{2}$



Phasor diagram for  $\phi = \pi$



For  $N = 8$ , there are a total of 7 minima with

$$\phi = \frac{\pi}{4}, \frac{2\pi}{4}, \frac{3\pi}{4}, \frac{4\pi}{4}, \frac{5\pi}{4}, \frac{6\pi}{4}, \frac{7\pi}{4} = m \frac{2\pi}{N}, m = 1, \dots, N-1$$